

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Attn: APPLICATION BRANCH**
Akihisa HONGO et al. : Attorney Docket No. 2003_0979
Serial No. NEW :
Filed July 17, 2003 :

WAFER CLEANING APPARATUS
(Rule 1.53(b) Divisional
of Serial No. 09/572,432,
Filed May 17, 2000)

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ACCOUNT NO. 23-0975

CLAIM OF PRIORITY UNDER 35 USC 119

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japan Patent Application No. 11-139183, filed May 19, 1999, as acknowledged in the Declaration of this application.

A certified copy of said Japan Patent Application is of record in parent application Serial No. 09/572,432, filed May 17, 2003.

Respectfully submitted,

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